Characterisation of TIBr Crystals for Detector Applications



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Detector properties



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- Crystal quality
- Purity (composition)
- Previous study* =>
- Chemical aspects
- Crystal growth
- Purification
- * V. Kozlov, M. Leskelä, T. Prohaska, G. Schultheis, G. Stingeder and H. Sipilä, Nucl. Instr. and Meth. A (2004) (in press)

This study => Crystal quality

- Crystal growth
- Annealing (+hydrothermal)
- Methods:
- X-ray rocking curve
- IV & photo-current
- X-ray Cu-radiation
- Polarisation microscope



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Sample production from the ingot and wafer mapping





- Two large crystals of diameter 21 mm were grown using Bridgman method
- •<= Reference surface: plane (100) or (111)
- Wafers and, then, slices were cut as is presented in Figure

Rocking curve mapping







Annealing: FWHM change

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150°C

1.2

0.5

1.4

8.0

Ar atmosphere

An03	Src	200°C
SL02(111)	0.6	0.6
SL05(100)	2.8	1.4
SL06(211)	ND	0.7

Pure waterAn04Src13(1)1(1)2.513(1)2(1)1.313(2)1(1)1.813(2)2(1)1.2

Abr.:	
ND	- not detected
13(1)	- (111) planes
13(2)	- (100) planes

An05	Src	225°C
13(1)3(1)	0.7	0.2
13(1)4(1)	0.65	0.2
13(2)2(2)	2.7	0.35
13(2)3(1)	2.5	0.35



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Effects of hydrothermal annealing during 5 days



150° C

225° C

Effect of TIBr crystal annealing



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- Source slice10 and annealed slice12
 - Sample rotation in Nicole crossed

rotation ~-5°

Source slice10 at a start position rotation ~+15°



-40°

Slice12 annealed at 225° C at a start position

rotation -42°

IV-measurements







Irradiation: 440nm

<= Dark box

+ "Dark" * 20

IV: Annealing





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- Annealing: Dry Ar, 200° C
- Annealing: water, 150° C (unstable characteristic)
- Annealing: water, 225° C (unstable characteristic)



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Photo-Current Spectra

1,0 SL02: Source 0,9 SL02: Ar, 200° C 0,8 Ratio of current: i / iMax An04B: water, 150° C 0,7 -An05C: water, 225° C 0,6 -0,5 0,4 0.3 0,2 0,1 0,0 200 250 300 350 400 450 500 550 600 wavelengh, nm

- Non annealed source
- Annealing: Ar, 200° C
- Annealing: water, 150° C
- Annealing: water, 225° C
- Normalisation by Max



X-ray response

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Annealing: Ar, 200° C

Annealing: water, 150° C

Annealing: water, 225° C

Conclusions



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- TIBr grown from melt is stressed and the block boundaries formed have complicated character
- Annealing improves the crystal quality and as result electrical, optical and detection properties
- Annealing in pure water asymmetrically modifies these properties that is probably caused by the concentration gradient of impurities
- Several samples annealed in pure water reveal characteristics of a semiconductor doped



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